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** FOREIGN APPLIC JAPAN 2000-36	ATIONS ************************************	****				
Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged Exa	773	STATE OR COUNTRY JAPAN	SHEETS DRAWING 7	TOTAL CLAIMS 20		
ADDRESS McDermott, Will & Em 600 13th Street, N.W. Washington ,DC 2000	•					
TITLE Polishing solution sup semiconductor substra	ply system, method of sate and method of manu	supplying polishing solu ufacturing semiconduct	ution, apparatu or device	s for and m	nethod of polishing	
RECEIVED No	: Authority has been given in Paperto charge/credit DEPOSIT ACCOUNTfor following:		1.1 1.1 1.1 1.1 1.1 1.1 1.1 1.1 1.1 1.1	All Fees 1.16 Fees (Filing) 1.17 Fees (Processing Ext. of time) 1.18 Fees (Issue) Other Credit		